



Indian Institute of Technology Guwahati

Research and Development Section

Guwahati-781039, Assam

Applications are invited for **Walk-in-interview** of the following post(s) for **Contractual recruitment** in the project entitled, "**Indian Nano electronics Users' Programme - Idea to Innovation (INUP-i2i)**" at **Centre for Nanotechnology, IIT Guwahati**.

Date: 9th June 2025 (Monday)

Time: 10:00 A.M

Venue: Conference Room, Centre for Nanotechnology, IIT Guwahati

Sl. No.	Project Staff Designation	Number of Vacancies	Pay Recommended (Rs.)	HRA Required (Rs.)	Medical Required (Rs.)	Total Amount (Rs.)	Duration of Appointment in months	Qualifications
1	SRF (DIRECT)	05	42,000.00	Yes 7,560.00	1,250.00	50,810.00	06	<p>Post Graduate in basic science or Graduate/Post Graduate in Professional Course selected through a process described through any one of the following:</p> <ol style="list-style-type: none">Scholars selected through National Eligibility Test-CSIR-UGC NET including Lectureship (Assistant Professors hip) and GATE.The selection process through National Level Examinations conducted by Central Government Departments and their Agencies and institutions such as DST, DBT, DAE, DOs, DRDO, MHRD, ICAR, ICMR, IISc, IISCR etc.+2yrs of Research Exp. <p>Preferable requirements: Expertise in NanoScience, Nanotechnology, Nanobiology, Nanoelectronics and hands-on-experience in Nanofabrication and characterization (such as AFM, SEM, TEM, XRD, Electro-Spinning Device, Materials Printing System, Wire Bonding, Double Sided Mask Aligner, Thermal/E-Beam Evaporation,</p>

								RF Magnetron Sputtering Unit, Oxidation/Diffusion Furnaces, Reactive Ion Etching, FESEM-EBL, Mask Writer, Raman, IR.
2	Project Engineer	01	57,340.00	Yes 10321.20	1250.0	68911.2	11	<p>PhD degree Or Master`s degree in Engineering + 3 yrs exp. Or Bachelor`s degree in Engineering + 6 yrs exp</p> <p>Preferable Experience: Training, Operation and Maintenance of Mask Writer, Mask Aligner and E-Beam Lithography, AFM, SEM, TEM, XRD, Wire Bonding, Double Sided Mask Aligner, Thermal/E-Beam Evaporation, RF Magnetron Sputtering Unit, Oxidation/Diffusion Furnaces, Reactive Ion Etching, FESEM-EBL, Mask Writer, Raman, IR.</p>
3	Associate Project Engineer	01	42,700.00	Yes 7686.00	1250.00	51636.00	11	<p>Master`s degree Engineering/ Or Bachelor`s degree in Engineering + 3 yrs exp.</p> <p>Preferable Experience: Training, Operation and Maintenance of high end equipment such as AFM, SEM, TEM, XRD, Electro-Spinning Device, Materials Printing System, Wire Bonding, Double Sided Mask Aligner, Thermal/E-Beam Evaporation, RF Magnetron Sputtering Unit, Oxidation/Diffusion Furnaces, Reactive Ion Etching, FESEM-EBL, Mask Writer, Raman, IR and will also maintain the Web page for the online applications.</p>
4	Assistant Project Engineer	01	34,770.00	Yes 6258.6	1250.00	42278.60	11	<p>Bachelor`s degree in Engineering.</p> <p>Preferable Experience: Operation and Maintenance of AFM, Raman, UV-Vis Spectra, Fuel Cell Testing Facility, Mask Writer, Mask Aligner, and E-Beam Lithography. They will also maintain the Web page for the online applications.</p>

How to apply and selection process: Candidates have to appear in the Walk in Interview along with an application/CV on plain paper giving details of all educational qualifications, experience, contact address, phone no., E- mail etc. and submit photocopies of relevant documents at the time of interview on 9 June 2025 (Monday) at 10:00 am. Venue: Centre for Nanotechnology.

Selection will be based on the performance of the candidate in the interview. Candidates will not be sent any call letter separately. Advance copy of CV may be sent to the Principal Investigator.

For any clarification, contact: Nano Office, Centre for Nanotechnology, IIT Guwahati

Email: nano_off@iitg.ac.in

Phone: 03612583066/3075

No campus accommodation will be available for the selected candidates and no TA/DA will be paid to the candidates for appearing in the test and interview.

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Assistant Registrar (R&D)